



Optical Photon Processes

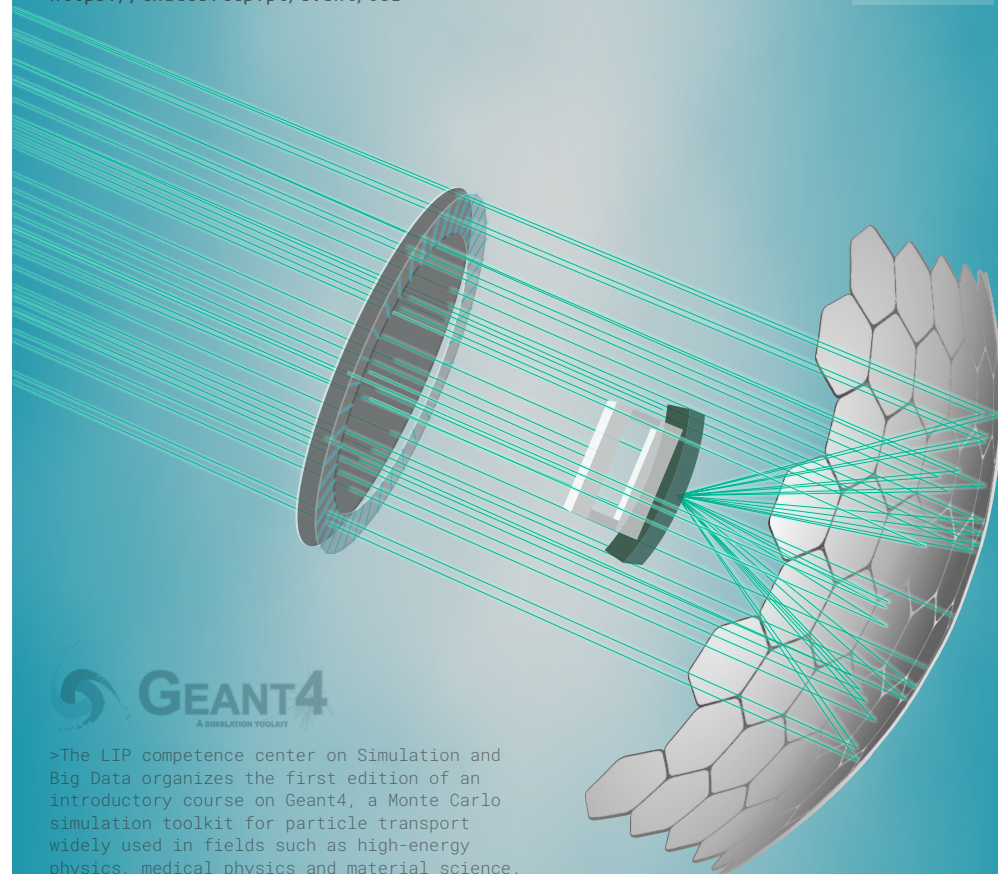
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Slides adapted from slides produced by :
Marc Verderi, Dennis Wright, Vladimir Ivantchenko, Mihaly Novak
<http://cern.ch/geant4>



INTRODUCTORY COURSE ON GEANT4

11-13 February 2020
University of Minho
Gualtar Campus, Braga
<https://indico.lip.pt/event/681>



>The LIP competence center on Simulation and Big Data organizes the first edition of an introductory course on Geant4, a Monte Carlo simulation toolkit for particle transport widely used in fields such as high-energy physics, medical physics and material science.

Organizing committee:

N. Castro, P. Gonçalves, A. Lindote, R. Sarmiento, B. Tomé, M. Vasilevskiy

Optical processes

- Propagation of optical photons and their interaction with materials is treated separately from regular electromagnetic processes :
 - Wavelengths are much larger than atomic spacing
 - Treated (partially) as waves; no smooth transition to gammas
 - Energy/momentum not generally conserved in G4 optics !
- Optical photons produced directly by three processes :
 - G4Cerenkov
 - G4Scintillation
 - G4TransitionRadiation

Optical photon transport

- Optical photons can undergo:
 - Refraction and reflection at boundaries
 - Wavelength shifting
 - Bulk absorption
 - Rayleigh scattering
- Material **optical** properties can be specified in a **G4MaterialsPropertiesTable** attached to **G4Material**
 - transmission efficiency, dielectric constants, surface properties
 - including binned wavelength/energy dependences
- Spectral properties can be also specified in **G4MaterialsPropertiesTable**
 - scintillation yield, time structure (fast, slow components)

Note : an optical photon will not be propagated (killed) in a material without index of refraction

Specification of material optical properties

```
const G4int NUMENTRIES = 3;

G4double ppckov[NUMENTRIES]      = {2.034*eV, 3.*eV, 4.136*eV};
G4double rindex[NUMENTRIES]      = {1.3435, 1.351, 1.3608};
G4double absorption[NUMENTRIES] = {344.8*cm, 850.*cm, 1450.0*cm};

G4MaterialPropertiesTable* MPT = new G4MaterialPropertiesTable();

MPT->AddConstProperty("SCINTILLATIONYIELD", 100./MeV);

MPT->AddProperty("RINDEX", ppckov, rindex, NUMENTRIES)->SetSpline(true);
MPT->AddProperty("ABSLLENGTH", ppckov, absorption, NUMENTRIES)->SetSpline(true);

scintillator -> SetMaterialPropertiesTable(MPT);
```

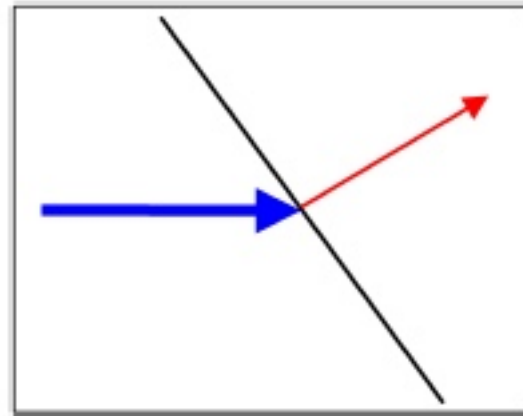
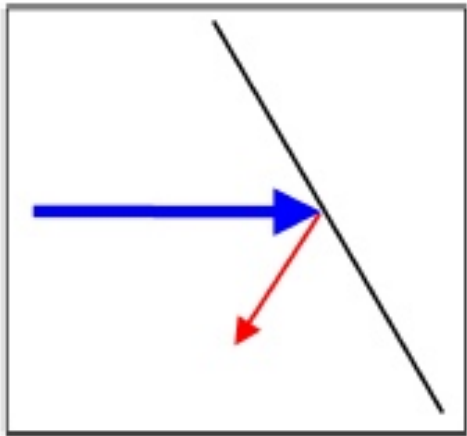
Optical boundary processes

- Refraction and reflection handled by **G4OpBoundaryProcess**
 - Boundary properties
 - dielectric-dielectric
 - dielectric-metal
 - dielectric-black material
 - Surface properties
 - polished
 - ground
 - front- or back- painted

User must supply surface properties through `G4OpticalSurfaceModel`

Reflection and Refraction

- Geant4 reflects “particle-like” behavior – no “splitting” of tracks



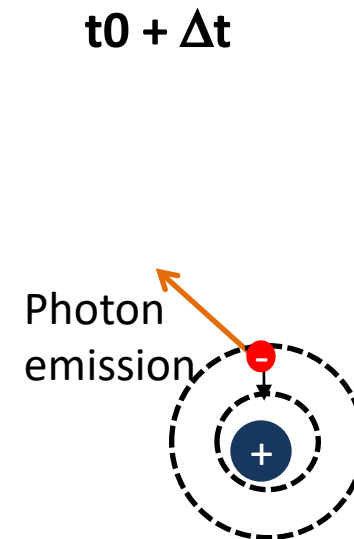
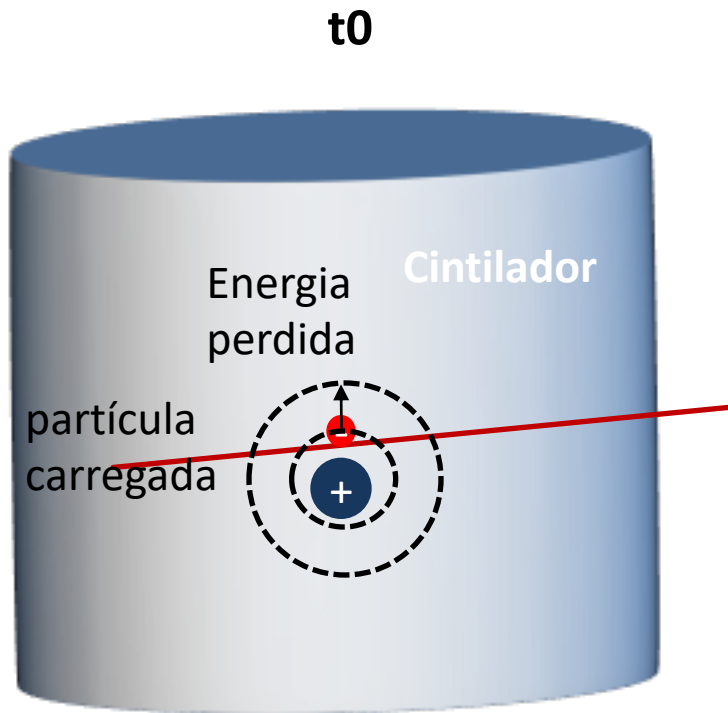
- Probability for transmission/reflection computed from Fresnel's relations
- Interference effects, important in layers of thickness comparable with the wavelength, can only be accounted for by the empirical reflectivity factor for the surface

Optical bulk processes

- G4OpAbsorption
 - uses photon attenuation length from material properties to get mean free path
 - photon is simply killed after a selected path length
- G4OpRayleigh
 - elastic scattering including polarization of initial and final photons
 - builds its own physics table (for mean free path) using **G4MaterialTable**
 - may only be used for optical photons (a different process provided for gammas)

Optical processes : Scintillation

- In a scintillator material light is emitted when excitation energy is transferred to the material
 - isotropic emission
 - random linear polarization



Specification of scintillation properties

```
const G4int NUMENTRIES = 9;
G4double Scnt_PP[NUMENTRIES] = { 6.6*eV, 6.7*eV, 6.8*eV, 6.9*eV,
                                   7.0*eV, 7.1*eV, 7.2*eV, 7.3*eV, 7.4*eV };

G4double Scnt_FAST[NUMENTRIES] = { 0.000134, 0.004432, 0.053991, 0.241971,
                                     0.398942, 0.000134, 0.004432, 0.053991,
                                     0.241971 };
G4double Scnt_SLOW[NUMENTRIES] = { 0.000010, 0.000020, 0.000030, 0.004000,
                                     0.008000, 0.005000, 0.020000, 0.001000,
                                     0.000010 };

G4Material* Scnt;
G4MaterialPropertiesTable* Scnt_MPT = new G4MaterialPropertiesTable();

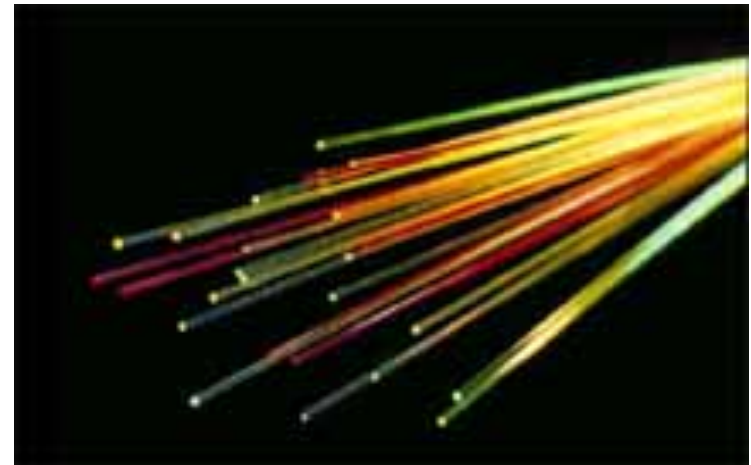
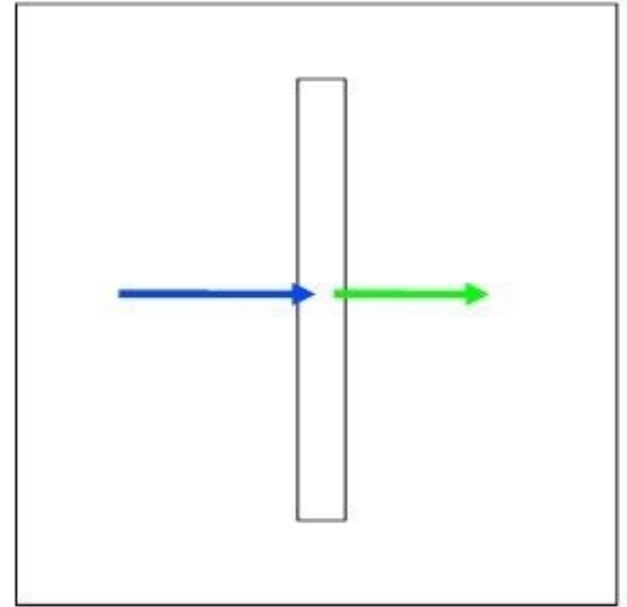
Scnt_MPT->AddProperty("FASTCOMPONENT", Scnt_PP, Scnt_FAST, NUMENTRIES);
Scnt_MPT->AddProperty("SLOWCOMPONENT", Scnt_PP, Scnt_SLOW, NUMENTRIES);

Scnt_MPT->AddConstProperty("SCINTILLATIONYIELD", 5000./MeV);
Scnt_MPT->AddConstProperty("RESOLUTIONSCALE", 2.0);
Scnt_MPT->AddConstProperty("FASTTIMECONSTANT", 1.*ns);
Scnt_MPT->AddConstProperty("SLOWTIMECONSTANT", 10.*ns);
Scnt_MPT->AddConstProperty("YIELDRATIO", 0.8);

Scnt->SetMaterialPropertiesTable(Scnt_MPT);
```

Optical processes : Wavelength Shifting

- In a WLS material light is absorbed and reemitted with a longer wavelength
 - isotropic emission
 - random linear polarization
- Handled by G40pWLS process
 - initial photon is killed, one with new wavelength is created
- User must supply :
 - absorption length in function of photon energy
 - emission spectra parameters as function of energy
 - time delay between absorption and re-emission



Specification of WLS properties

```
const G4int nEntries = 9;

G4double PhotonEnergy[nEntries] = { 6.6*eV, 6.7*eV, 6.8*eV, 6.9*eV,
                                     7.0*eV, 7.1*eV, 7.2*eV, 7.3*eV, 7.4*eV };

G4double RIndexFiber[nEntries] =
    { 1.60, 1.60, 1.60, 1.60, 1.60, 1.60, 1.60, 1.60, 1.60 };
G4double AbsFiber[nEntries] =
    { 0.1*mm, 0.2*mm, 0.3*mm, 0.4*cm, 1.0*cm, 10*cm, 1.0*m, 10.0*m, 10.0*m };
G4double EmissionFiber[nEntries] =
    { 0.0, 0.0, 0.0, 0.1, 0.5, 1.0, 5.0, 10.0, 10.0 };

G4Material* WLSFiber;
G4MaterialPropertiesTable* MPTFiber = new G4MaterialPropertiesTable();

MPTFiber->AddProperty("RINDEX", PhotonEnergy, RIndexFiber, nEntries);
MPTFiber->AddProperty("WLSABSLLENGTH", PhotonEnergy, AbsFiber, nEntries);
MPTFiber->AddProperty("WLSCOMPONENT", PhotonEnergy, EmissionFiber, nEntries);
MPTFiber->AddConstProperty("WLSTIMECONSTANT", 0.5*ns);

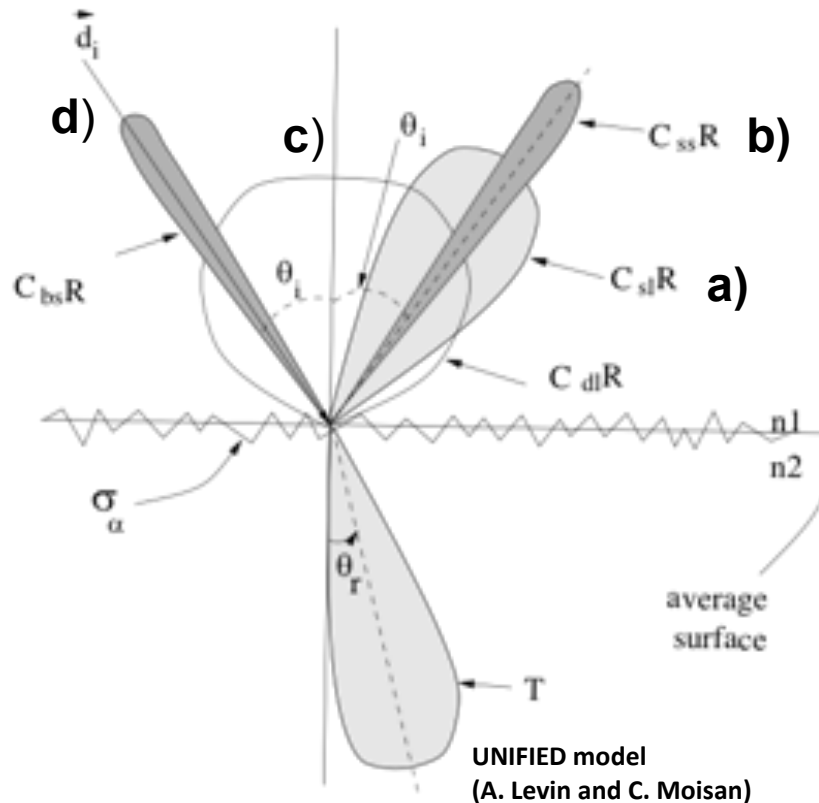
WLSFiber->SetMaterialPropertiesTable(MPTFiber);
```

Boundary processes :The Unified model

- Applies to dielectric-dielectric and dielectric-metal interfaces and tries to provide a realistic simulation, dealing with many aspects of surface finish and reflector coating :
 - surface may be assumed as smooth and covered with a metalized coating representing a specular reflector with given reflection coefficient
 - painted with a diffuse reflecting material where Lambertian reflection occurs.
 - surfaces may or may not be in optical contact with another component
 - a rough surface made up of micro-facets with normal vectors that follow given distributions around the nominal normal for the volume at the impact point.

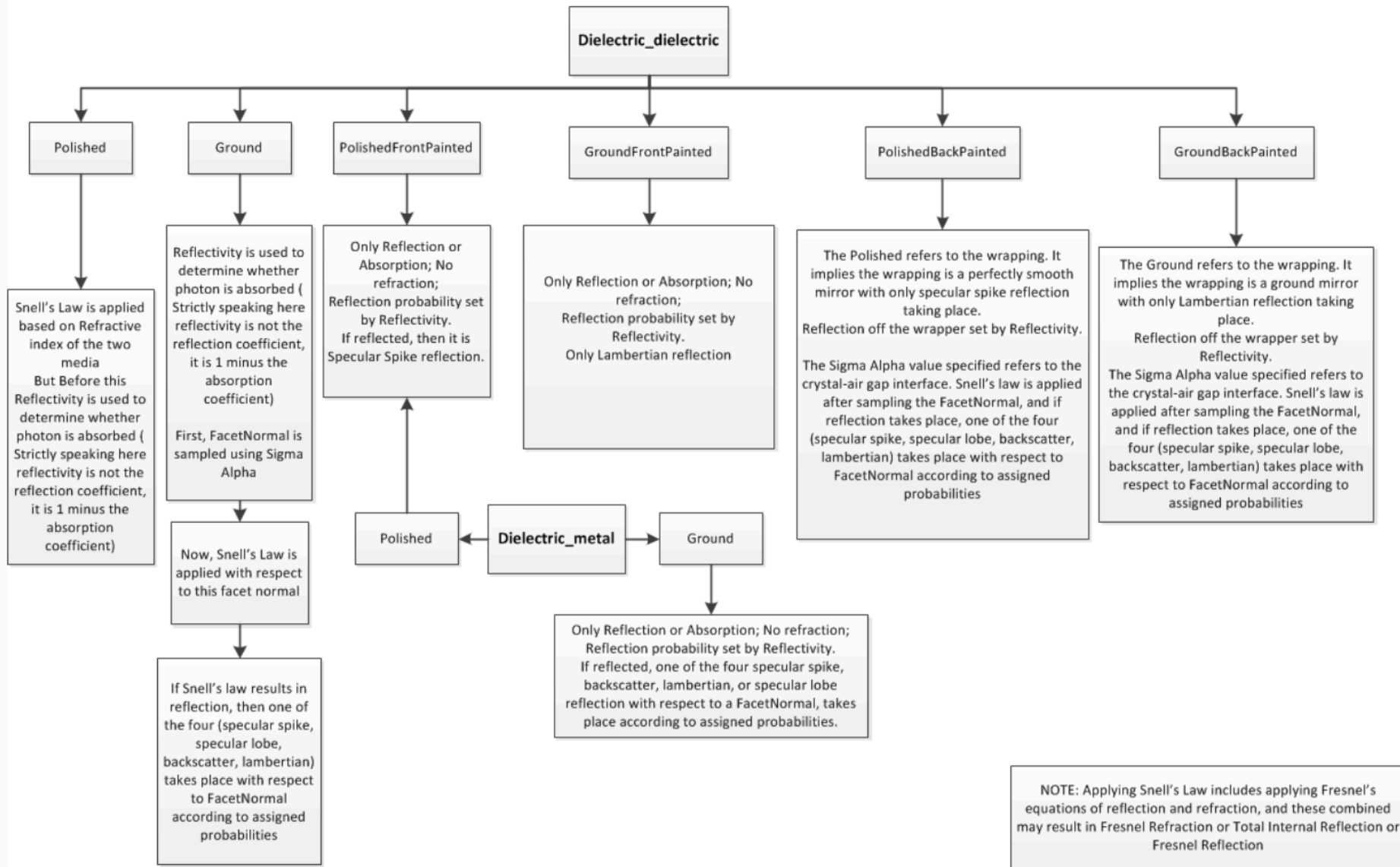
Boundary processes :The Unified model

Provides for a range of different reflection mechanisms.



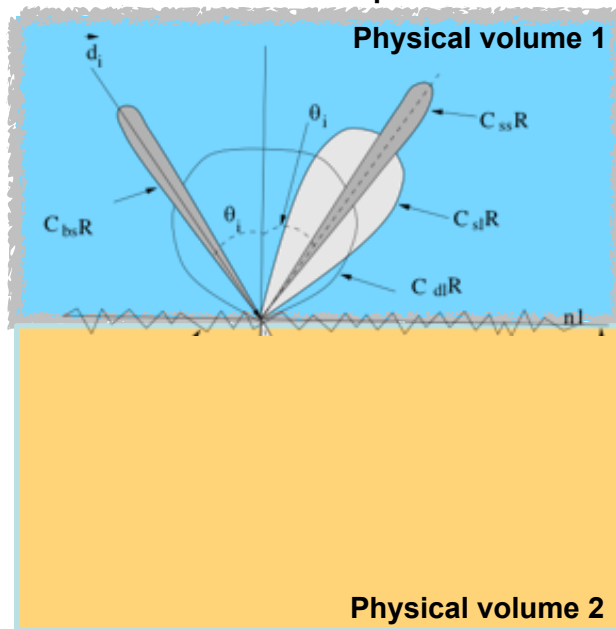
- a) specular lobe constant : reflection probability about the normal of a micro facet
- b) specular spike constant : the probability of reflection about the average surface normal.
- c) diffuse lobe constant is for the probability of internal Lambertian reflection
- d) back-scatter spike constant : several reflections within a deep groove with the ultimate result of exact back-scattering

Surface finishes



Example of specification of dielectric-dielectric surface properties

Ground backpainted



```
G4VPhysicalVolume* volume1;
G4VPhysicalVolume* volume2;

G4OpticalSurface* OpSurface = new G4OpticalSurface("name");

G4LogicalBorderSurface* Surface = new
    G4LogicalBorderSurface("name", volume1, volume2, OpSurface);

G4double sigma_alpha = 0.1;

OpSurface->SetType(dielectric_dielectric);
OpSurface->SetModel(unified);
OpSurface->SetFinish(groundbackpainted);
OpSurface->SetSigmaAlpha(sigma_alpha);

const G4int NUM = 2;

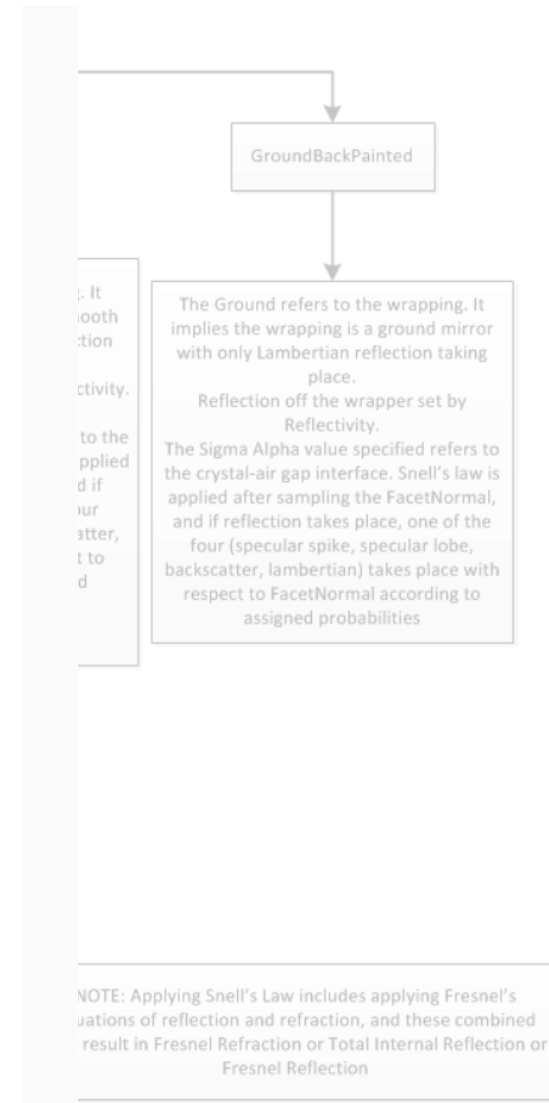
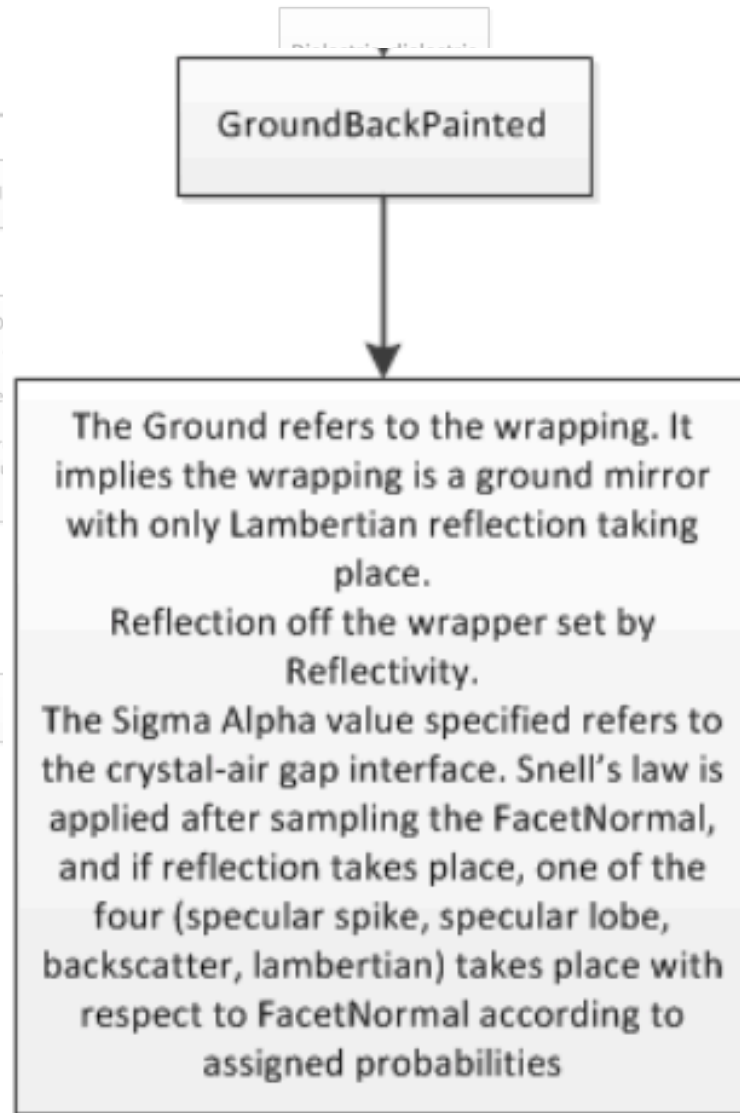
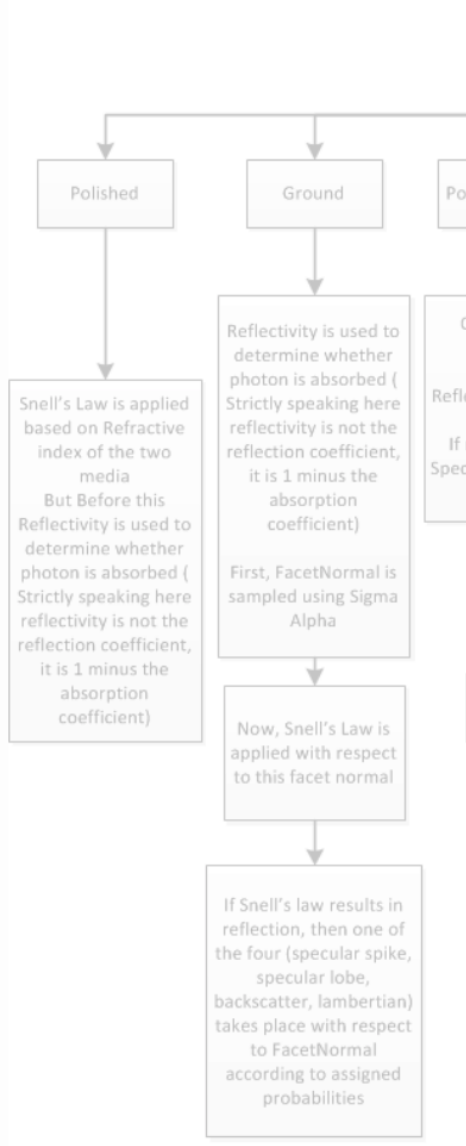
G4double pp[NUM] = {2.038*eV, 4.144*eV};
G4double specularlobe[NUM] = {0.3, 0.3};
G4double specularspike[NUM] = {0.2, 0.2};
G4double backscatter[NUM] = {0.1, 0.1};
G4double rindex[NUM] = {1.35, 1.40};
G4double reflectivity[NUM] = {0.3, 0.5};
G4double efficiency[NUM] = {0.8, 0.1};

G4MaterialPropertiesTable* SMPT = new G4MaterialPropertiesTable();

SMPT->AddProperty("RINDEX", pp, rindex, NUM);
SMPT->AddProperty("SPECULARLOBECONSTANT", pp, specularlobe, NUM);
SMPT->AddProperty("SPECULARSPIKECONSTANT", pp, specularspike, NUM);
SMPT->AddProperty("BACKSCATTERCONSTANT", pp, backscatter, NUM);
SMPT->AddProperty("REFLECTIVITY", pp, reflectivity, NUM);
SMPT->AddProperty("EFFICIENCY", pp, efficiency, NUM);

OpSurface->SetMaterialPropertiesTable(SMPT);
```

Surface finishes



Hands-On Optical Physics Processes

- We will use a new branch where part of the needed code is already inserted;
- Start by committing the modifications you inserted :
`git commit -am "My new code"`
- Fetch the new branch :
`git checkout step6-optics-0`

Let's make the crystal shine

- We are going to use the personalised modular physics list (class **PhysicsList**) to include the optical physics processes category; modify the code as appropriate to use this class and include the optical physics category;
- In the **DetectorConstruction()** inspect the function **SetMaterialOpticalProperties()**; it defines the optical properties table to be set to the NaI crystal,
- Choose a light yield such that a few ($\sim 10 - 100$) photons will be emitted for the typical energies of the radioactive sources being simulated.
- Run the simulation with the visualisation and the macro **gamma.mac**
- For a small number of gammas shot, you should see several photon tracks inside the crystal; if yes proceed to the next slide

Detecting the optical photons

We will assume that a photon is detected if it arrives at the back of the crystal :

- In the **SteppingAction** class check if a step occurred inside your volume of interest and if the particle is an **opticalphoton**;
- Additionally use the **Pre** or **PostStep** points as needed to check if the photon detection condition is met;
- Increment a variable in the EventAction to count the number of detected photons; kill the optical photon afterwards;
- At the end of the event, write the total number of detected photons (together with the already existing true and smeared energies) to the output file;
- Increase the crystal light yield (L.Y.) to about 3 photons / keV (of the order of the NaI L.Y. (1 photon / 26 eV) times a 10% overall efficiency;

Detecting the optical photons

- Run the program for a few thousands of events using **gamma.mac**;
- Plot the distribution for the number of detected photons;
- What do you think about the result ?

Improving the light collection

We will now wrap the NaI crystal with a white diffuser

- In the **DetectorConstruction** class the function **SetSurfaceOpticalProperties()** is used to set the optical properties of the wrapping material;
- At the end of the **Construct()** function you can find the placeholders to use the **G4LogicalBorderSurface constructor** to set the optical properties of the surface of the crystal;

Detecting the optical photons

- Run the program for a few thousands of events using **gamma.mac**;
- Plot the distribution for the number of detected photons;
- Try to fit a gaussian distribution to the total absorption peak and extract the resolution of our spectroscopy setup;
- Now run the macros with the isotopes and compare the results with what was obtained yesterday using the true energy deposition;